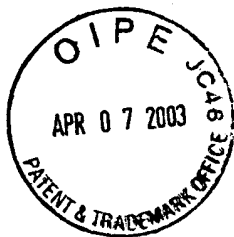


2878

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



Application No.: 09/639,495 Confirmation No.: Unknown  
First Named Inventor: Mehrdad Nikoonahad Filing Date: August 14, 2000  
Group Art Unit: 2878 Examiner: Unknown  
Atty. Docket No.: TNCR.181US0  
Title: METROLOGY SYSTEM USING OPTICAL PHASE  
Assignee: KLA-TENCOR CORPORATION

#8  
4/14/03  
[Signature]

San Francisco, California  
March 5, 2003

COMMISSIONER FOR PATENTS  
Washington, D. C. 20231

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SUPPLEMENTAL  
INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Pursuant to 37 C.F.R. §§ 1.56, 1.97, and 1.98, Applicants call the documents listed on the enclosed Form PTO-1449 to the Examiner's attention in this patent application.

☒ Copies of the documents listed on the accompanying Form PTO-1449 are enclosed.

Citation of these documents shall not be construed as (1) an admission that the documents are prior art with respect to the invention or inventions claimed in this application, (2) a representation that a search has been made (other than as indicated by any cited document), or (3) an admission that the cited information is, or is considered to be, material to patentability as defined in § 1.56(b).

This information disclosure statement is submitted under 37 C.F.R. § 1.97(b) and consequently no fee should be required.

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231, on March 31, 2003.

Valerie Olsen

Valerie Olsen

3/31/03

Date of Signature

Respectfully submitted,

James S. Hsue

Reg. No. 29,545

Attorney for Applicant(s)

U.S. Department of Commerce, Patent and Trademark Office				Atty Dock No.		Application No.	
				TNCR.181US0		09/639,495	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Applicant(s)		Confirmation No.	
(Use several sheets if necessary)				Mehrdad Nikoonahad, et al.		Unknown	
				Filing Date		Group	
				August 14, 2000		2878	

U.S. Patent Documents							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AD						
	AE						
	AF						
	AG						
	AI						
	AJ						
	AD						
	AE						
	AF						
	AG						
	AK						
	AD						
	AE						
	AG						
	AH						
	AI						

Foreign Patent Documents								
							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	AL							
	AM							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)		
AQ	R. Pforr, et al., "In-Process Image Detecting Technique For Determination Of Overlay, And Image Quality For ASM-L Wafer Stepper", SPIE Vol. 1674 Optical/Laser Microlithography V (1992) pp. 594-608	

Examiner	Date Considered
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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.